



## A NIR Pin-Hole Projection System: Status and Plans

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SNAP Site Visit

October 6, 2004

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Mike Schubnell, G. Tarlé, A. Tomasch)

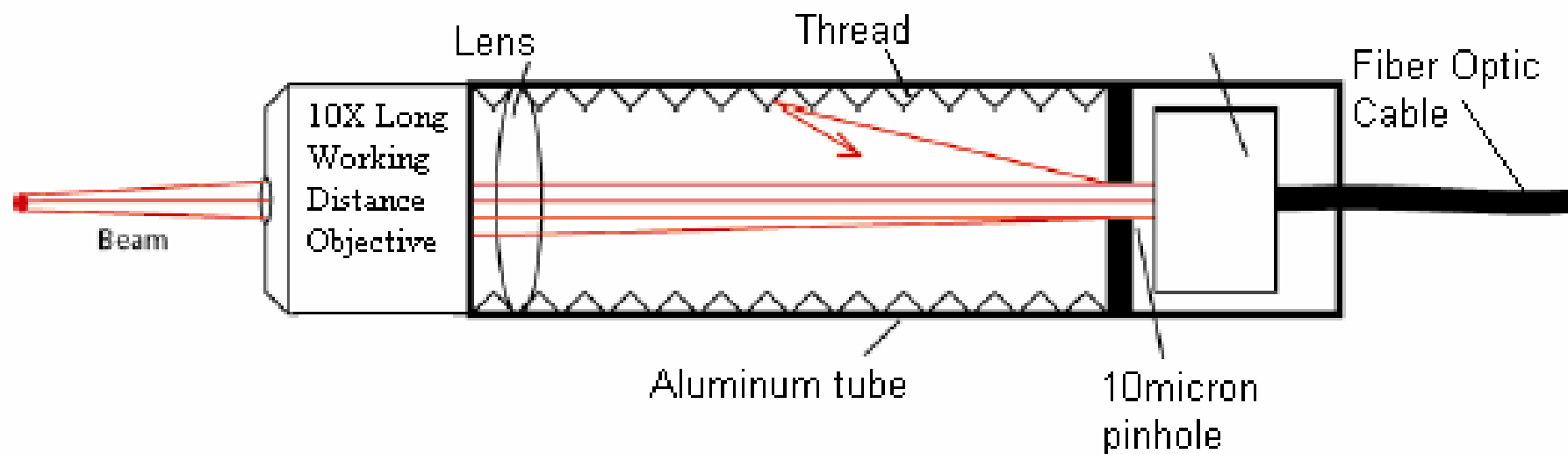
# Requirements

- Project  $\mu\text{m}$ -size NIR spots through dewar window onto detectors
  - be able to move spot around VERY precisely
  - achieve sub-pixel size reproducibility
  - maintain sub-percent intensity stability
  - be able to vary spot size
- Measure intra-pixel sensitivity variation
  - evaluate dithering schemes
  - test predictions in laboratory
    - ⇒ demonstrate required photometric accuracy
- Measure lateral charge diffusion

# Brief History

Start in April 2003

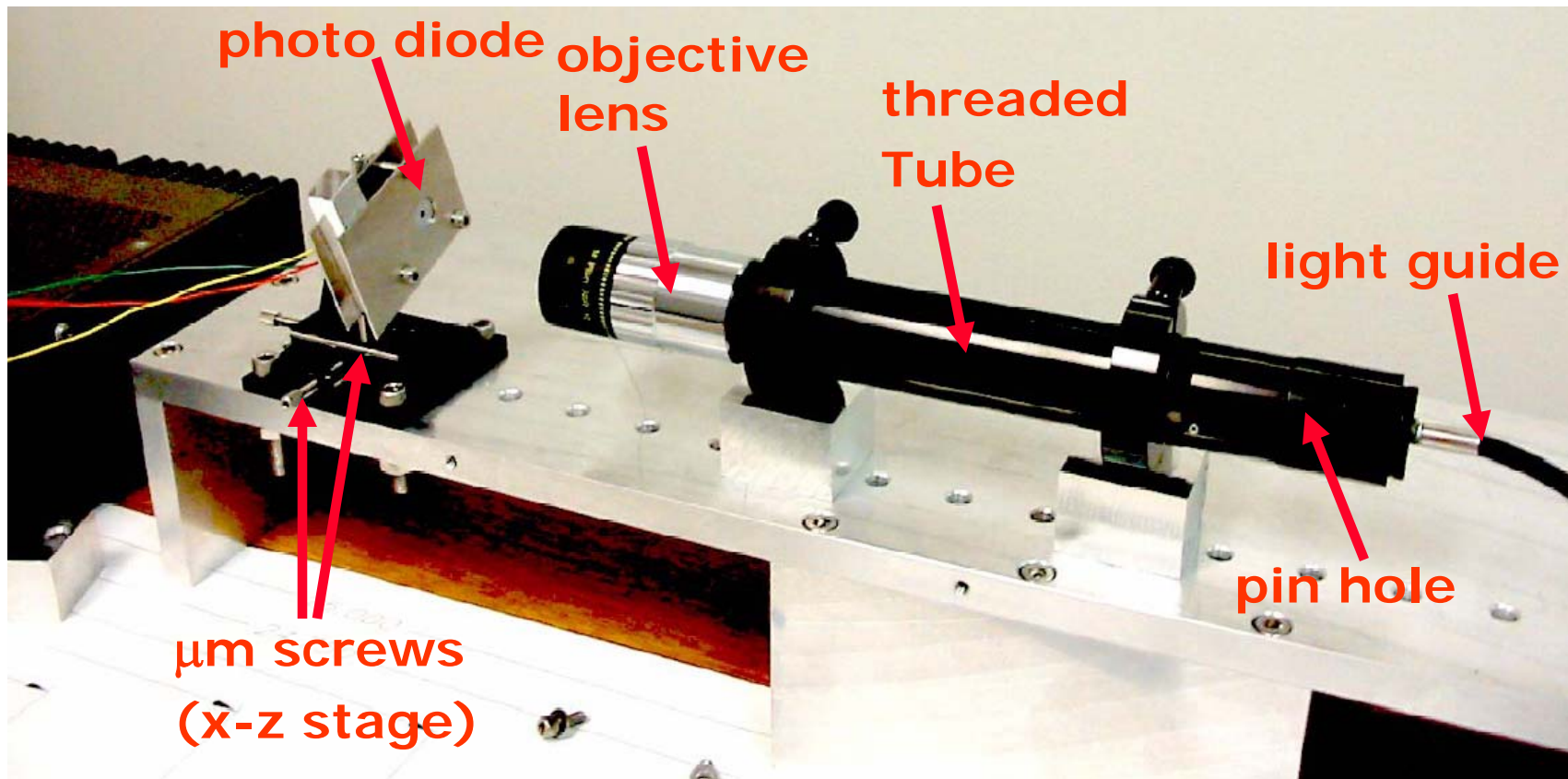
- base initial design on LBL pinhole projector (visible)
- adapt for NIR and improve design



Courtesy of W. Kolbe, LBL 2002

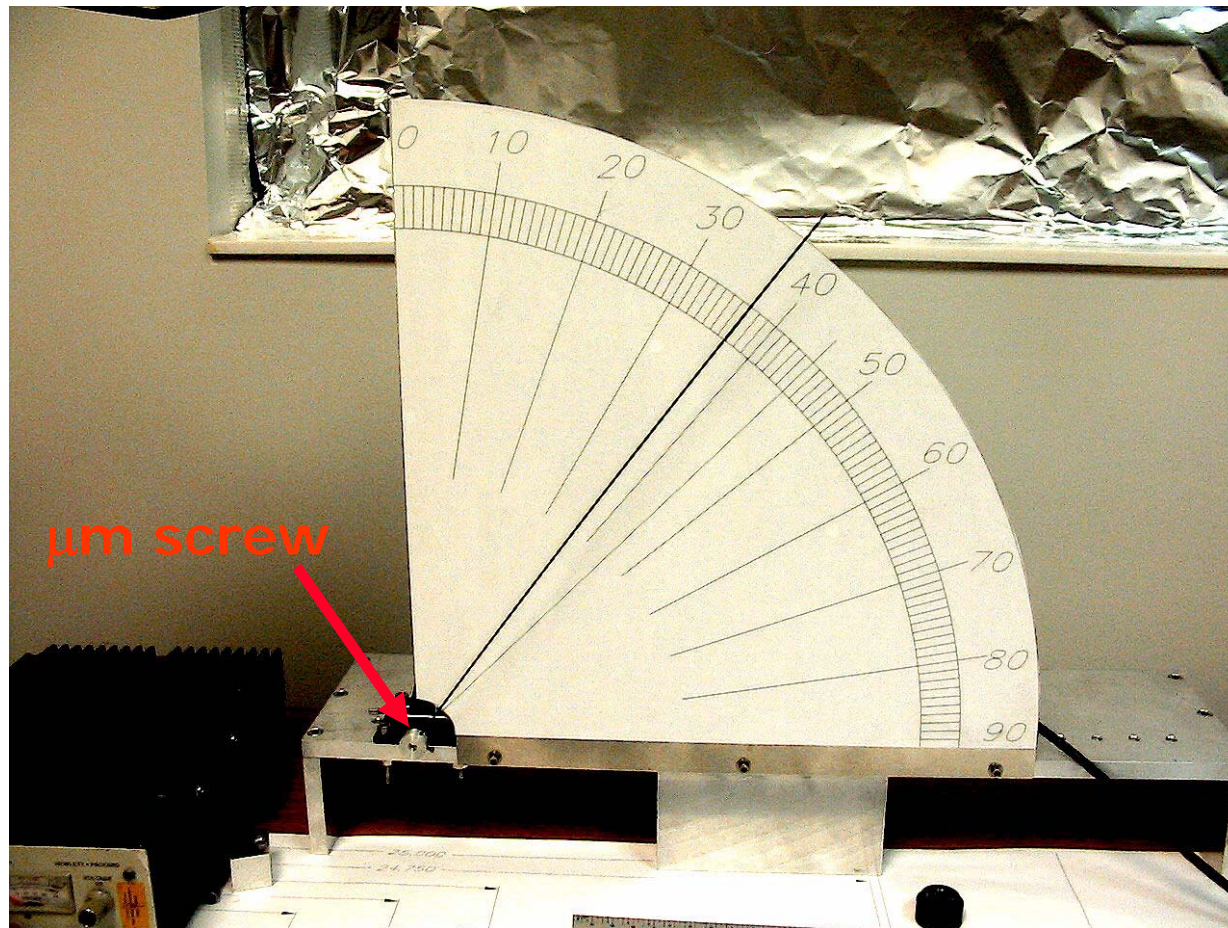
# REU Project: Summer 2003

Trying to find a focus



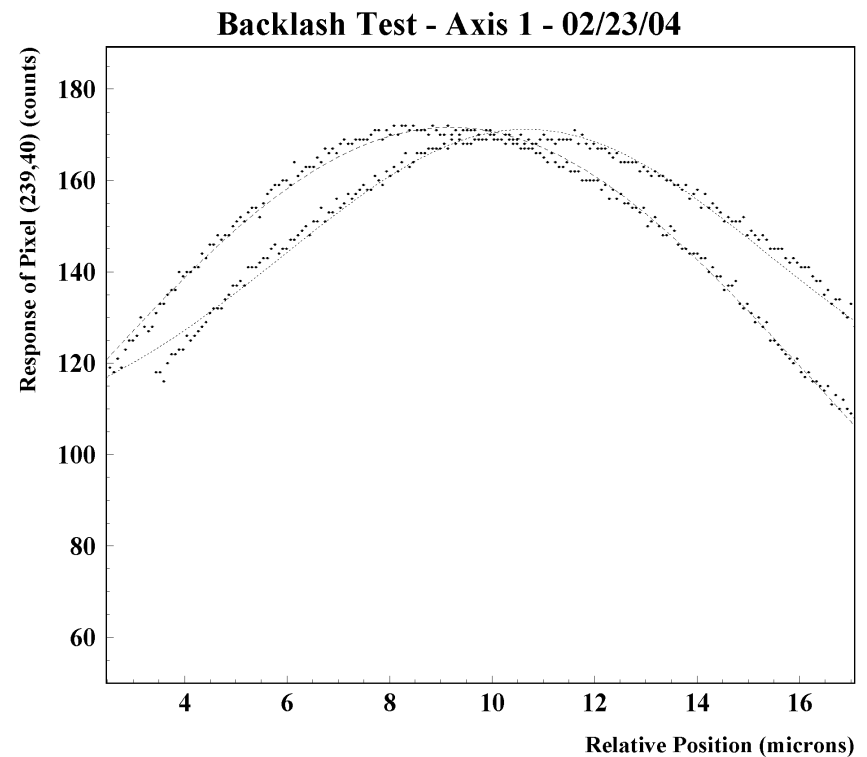
# REU Project: Summer 2003

Trying to move in small steps ( $\mu\text{m}$ )



# Senior Thesis Project: Winter 04 semester

- Installation of automated x-y-z stage
  - step size:  $0.075 \mu\text{m}$  ( $\pm 1 \text{ mm}$  per inch of travel)
- Characterization
  - backlash:  $1.0 - 1.5 \mu\text{m}$  (different for + or - direction)
    - correct in software
  - drift:  $0.3 \mu\text{m}$   
(similar for all 3 axes)
  - repeatability:  $0.3 \mu\text{m}$   
(similar for all 3 axes)



# Senior Thesis Project: Winter 04 semester

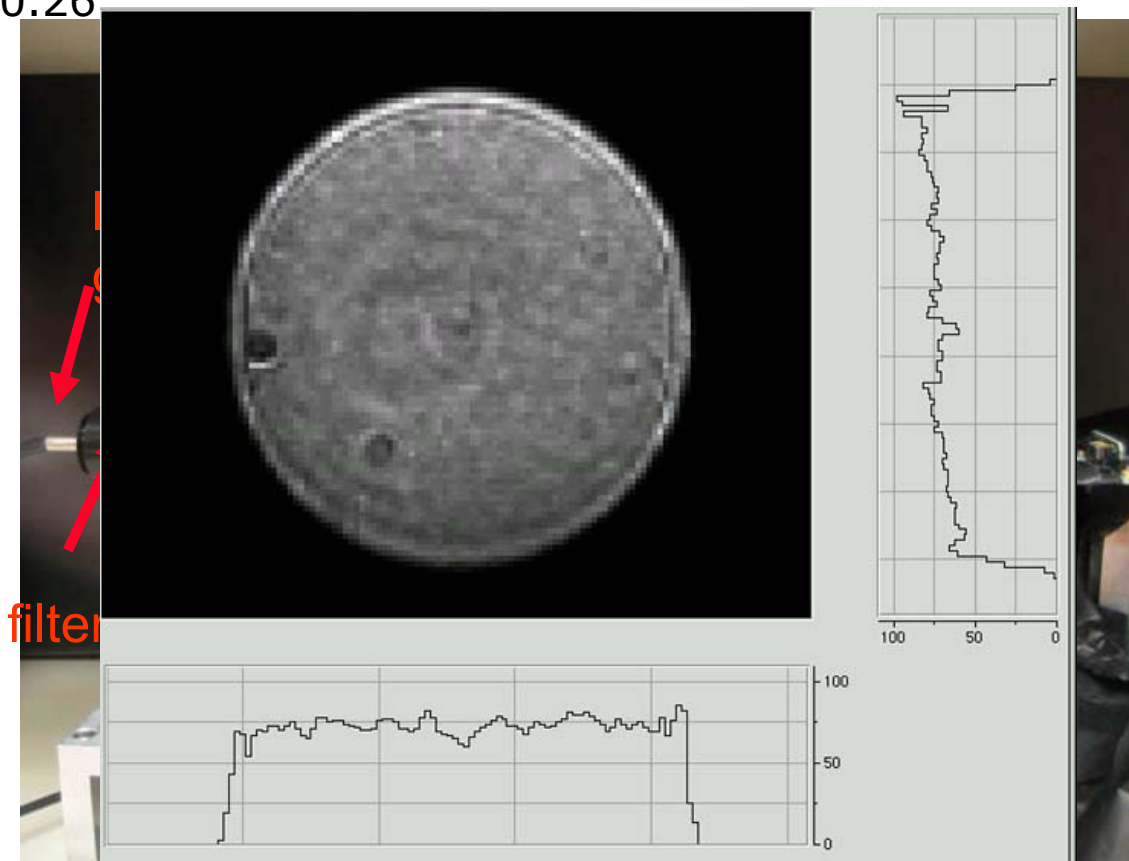
- Installation of optics

- M Plan NIR series (Mitutoyo Long Working distance objective)
- magnification (microscope configuration): 10x
- range (chromatically corrected): 480-1800 nm
- numerical aperture (NA): 0.26

⇒ minimal spot size [=f( $\lambda$ )]:  
**0.96 – 3.6  $\mu\text{m}$  ( $\sigma$ )**  
**2.25 – 8.44  $\mu\text{m}$  (FWHM)**

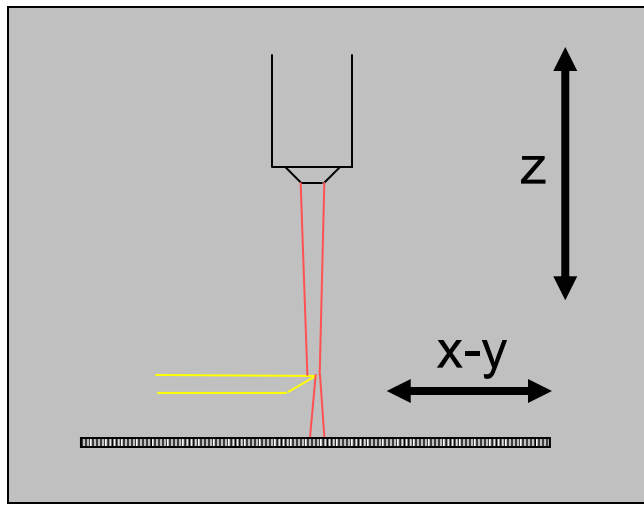
- Characterization

- understanding the optics using visible light on CCD
  - fighting bright spots
  - imaging pin holes
- knife edge scans
  - determining spot sizes

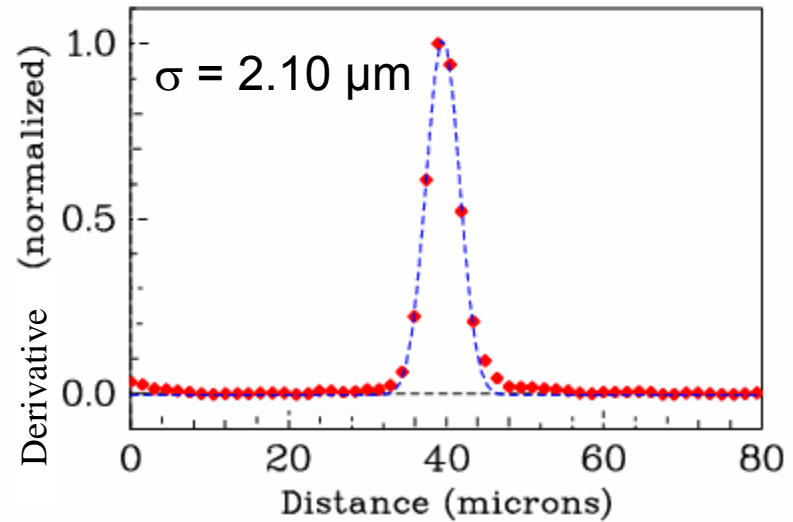
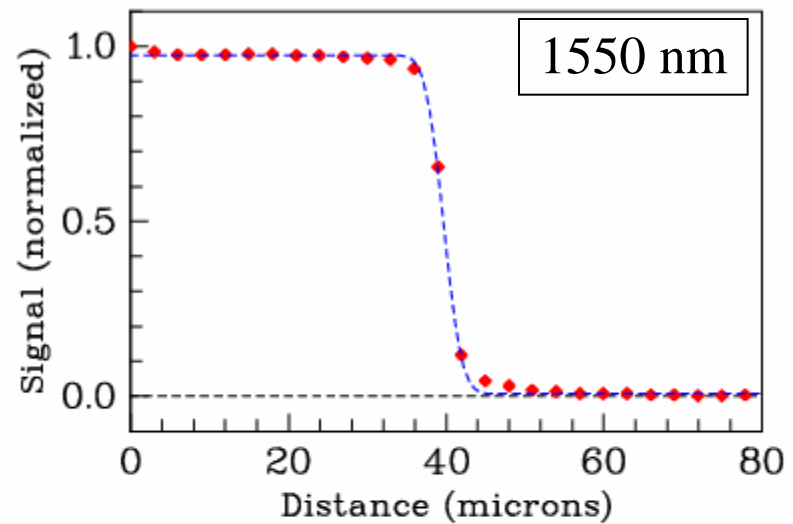


# Knife Edge Scan

- A knife edge is placed  $\sim 6$  mm above the detector surface
- Spot-O-Matic is scanned across knife edge in x-y while focusing in z to minimize the spot size and determine the point spread function (PSF)

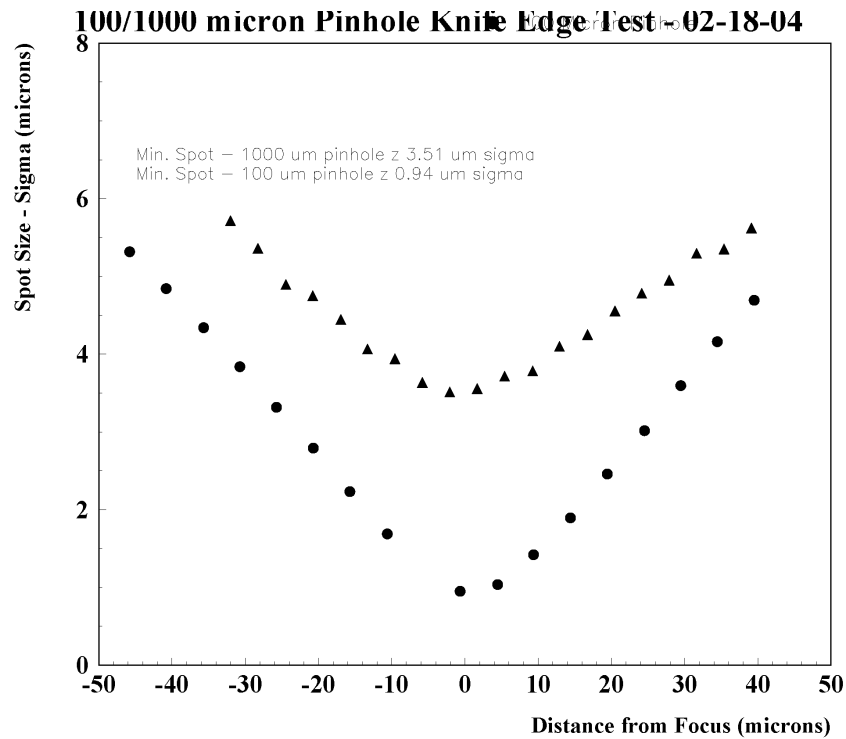


Best Focus

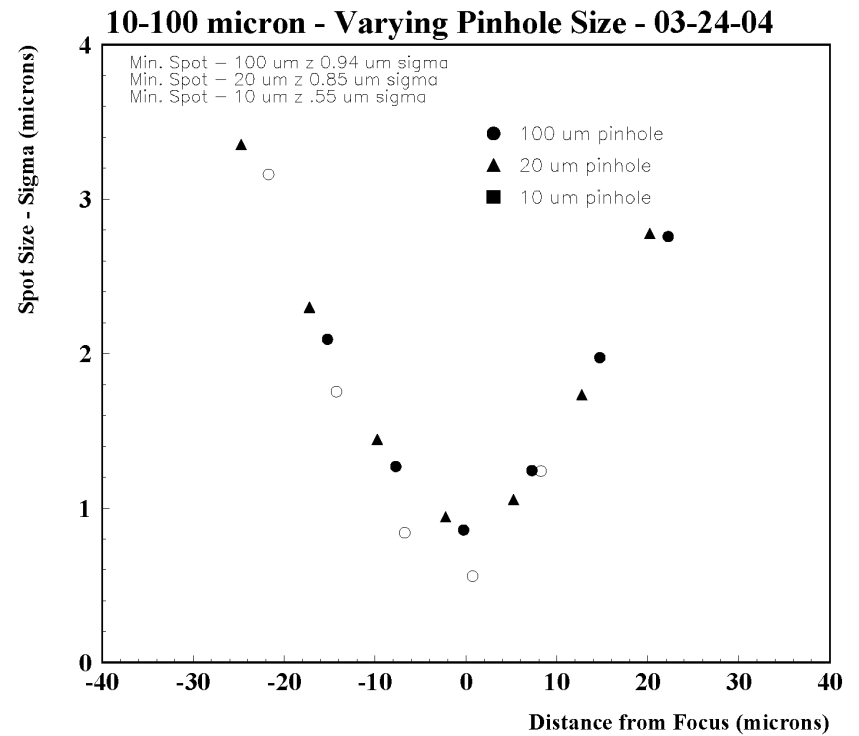




# Varying Pinhole Size

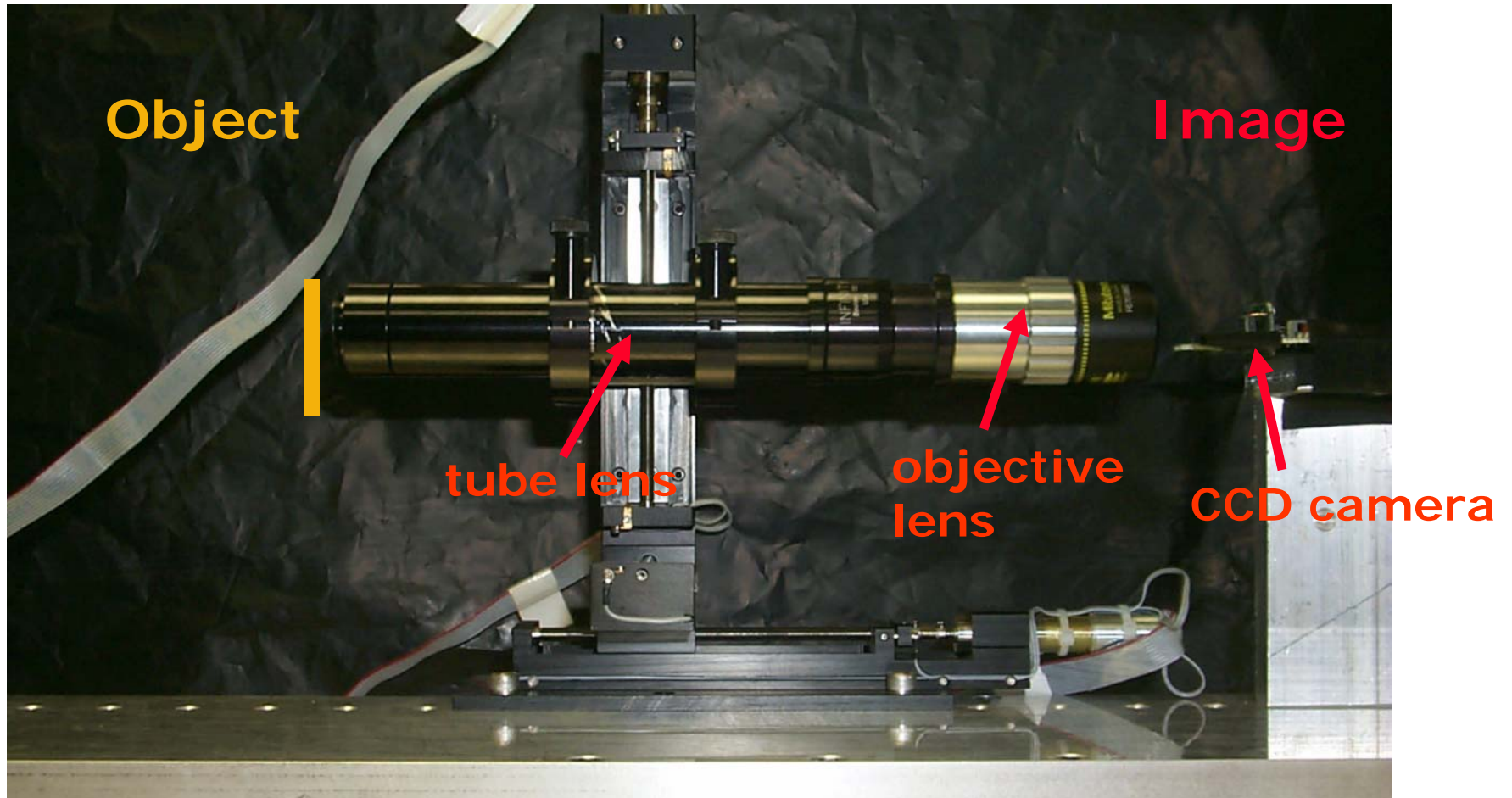


Expected behaviour

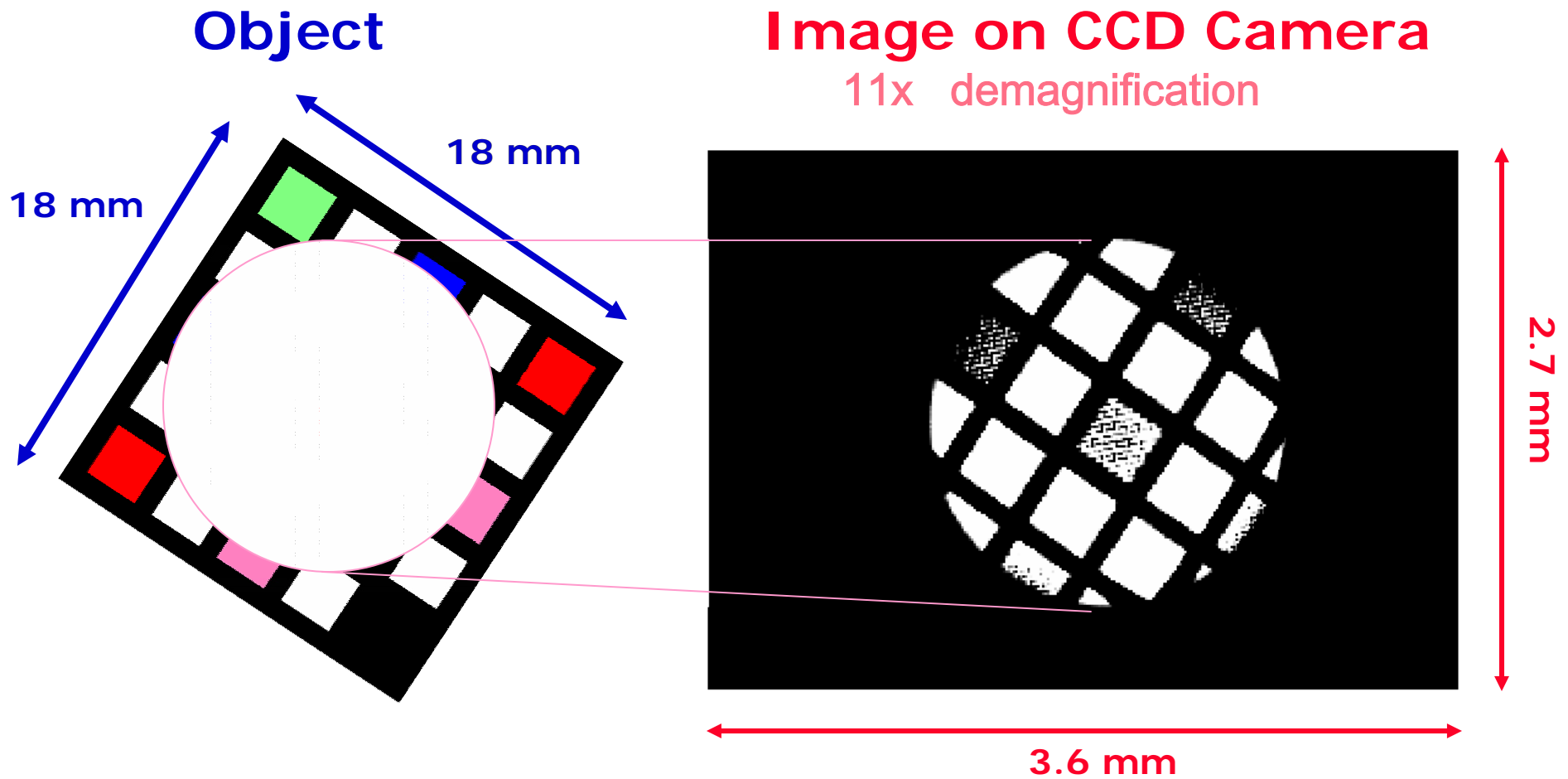


Unexpected behaviour

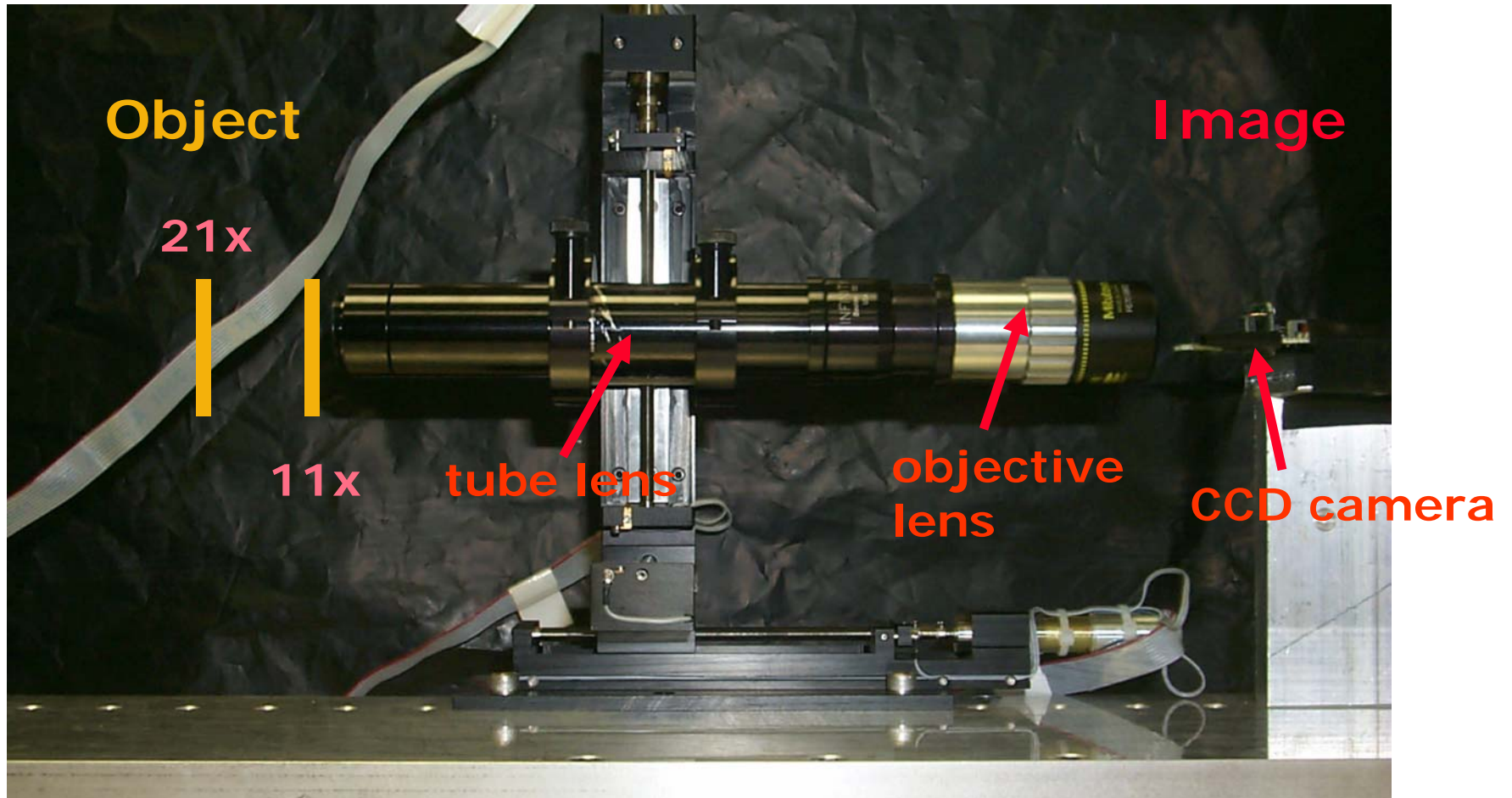
# Testing General Properties



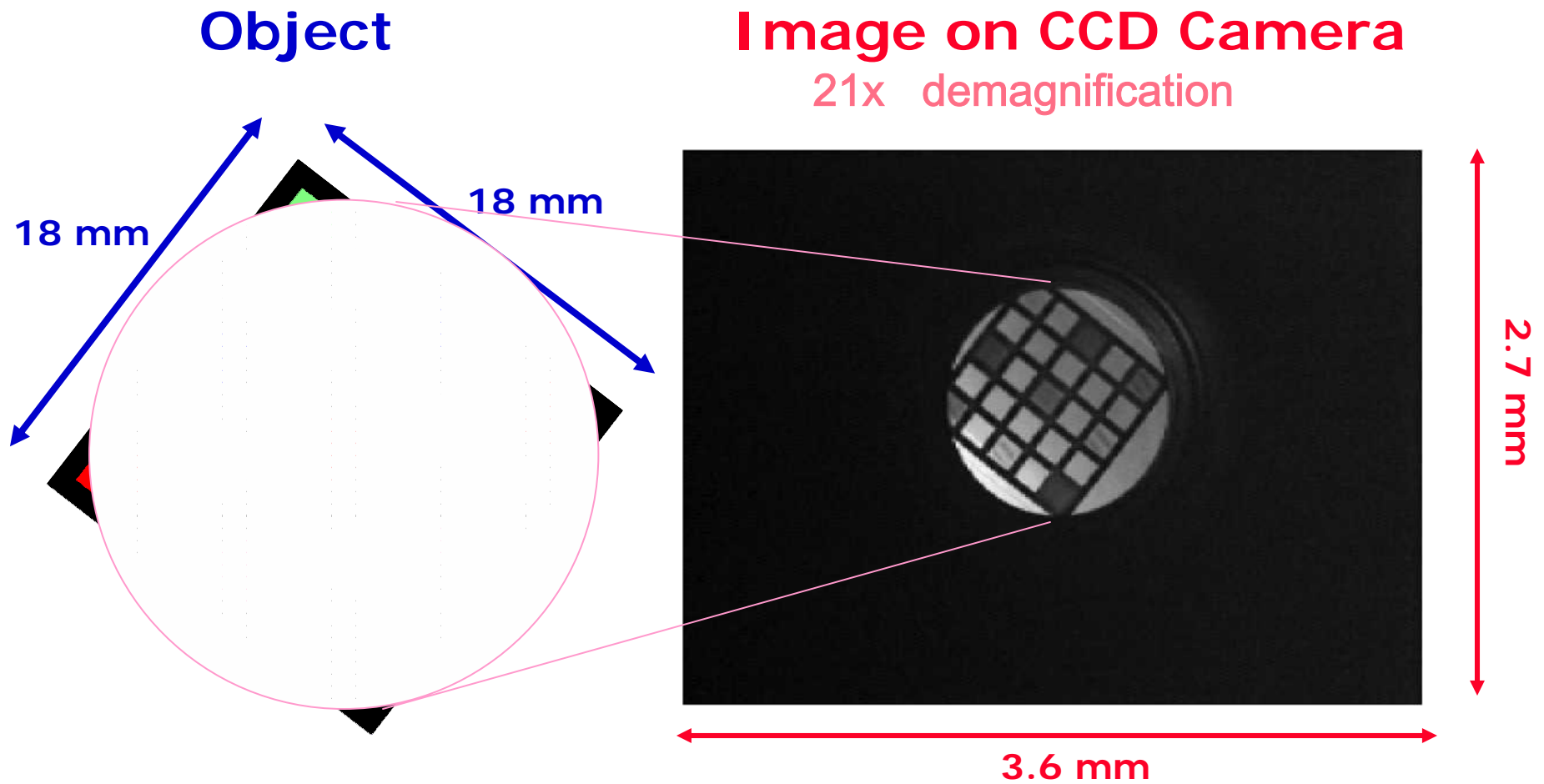
# Testing General Properties



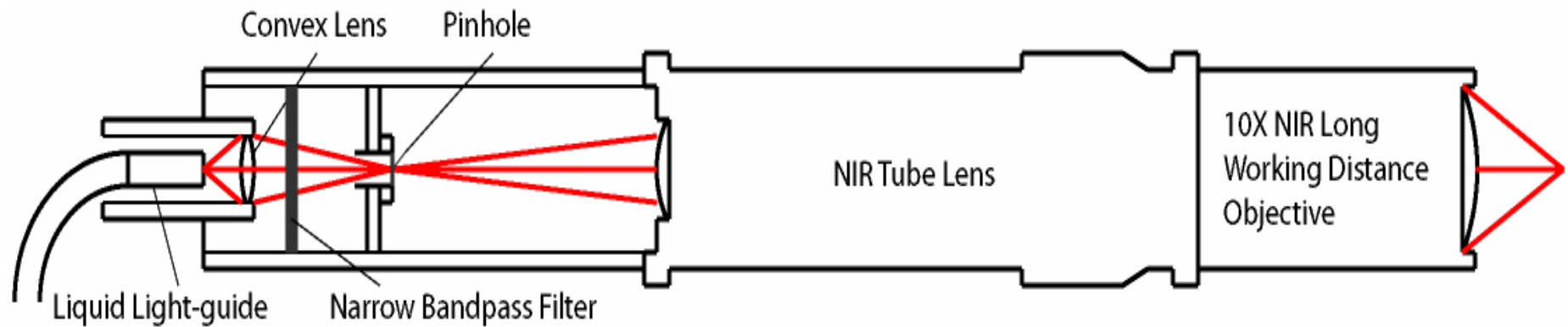
# Testing General Properties



# Testing General Properties



# How it Works



# Results

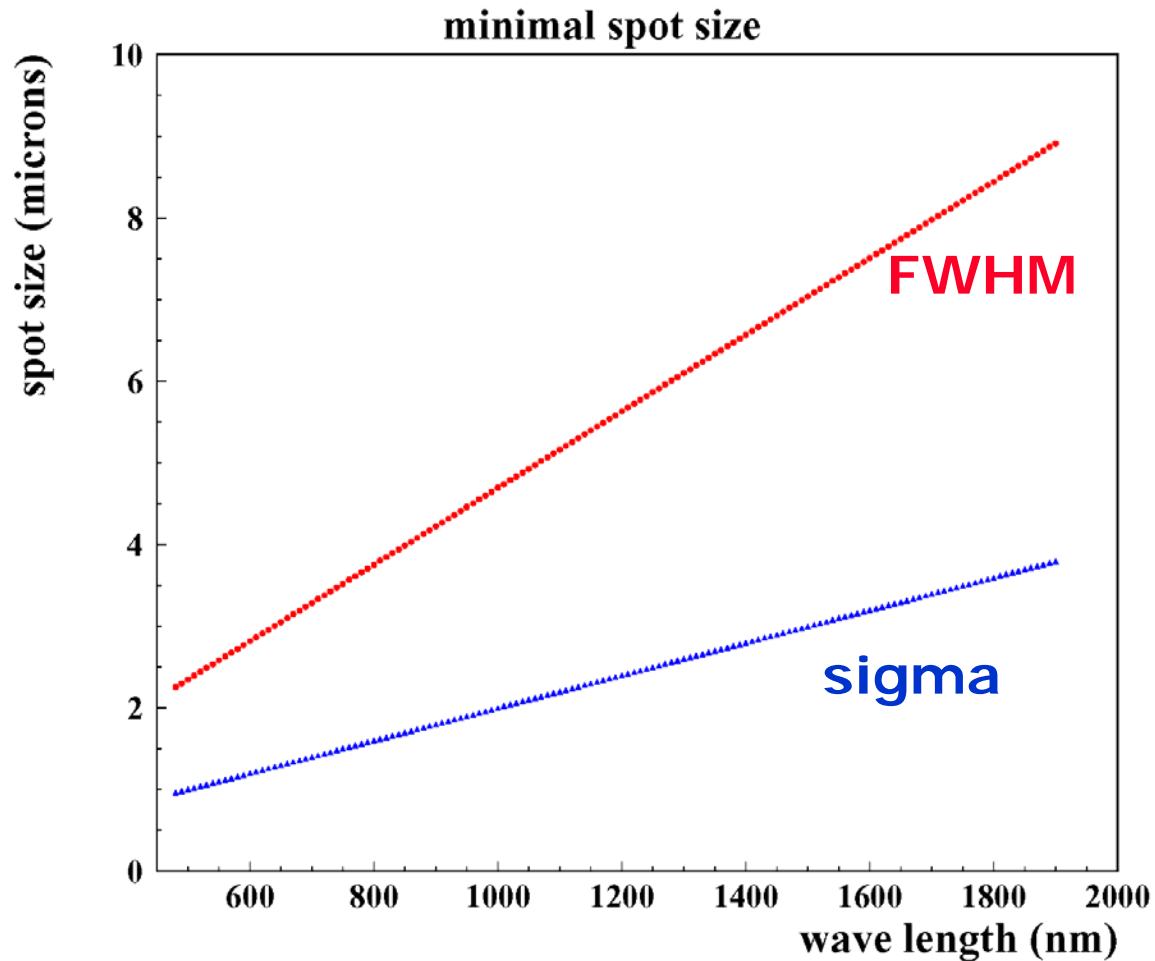
## Summary (visible light)

| Pinhole Size      | Smallest spot measured on CCD | Expected spot size (no diffraction) | Expected spot size (incl. diffraction) |
|-------------------|-------------------------------|-------------------------------------|--|
| 100 $\mu\text{m}$ | 5.9 $\mu\text{m}$             | 4.8 $\mu\text{m}$                   | 5.4 $\mu\text{m}$                      |
| 10 $\mu\text{m}$  | 2.5 $\mu\text{m}$             | 0.48 $\mu\text{m}$                  | 2.5 $\mu\text{m}$                      |

**Demagnification: 21x**

**Resolving Power =  $0.61 \lambda / N.A. \approx 1.2 \mu\text{m}$ .**

# Spot Size vs Wavelength

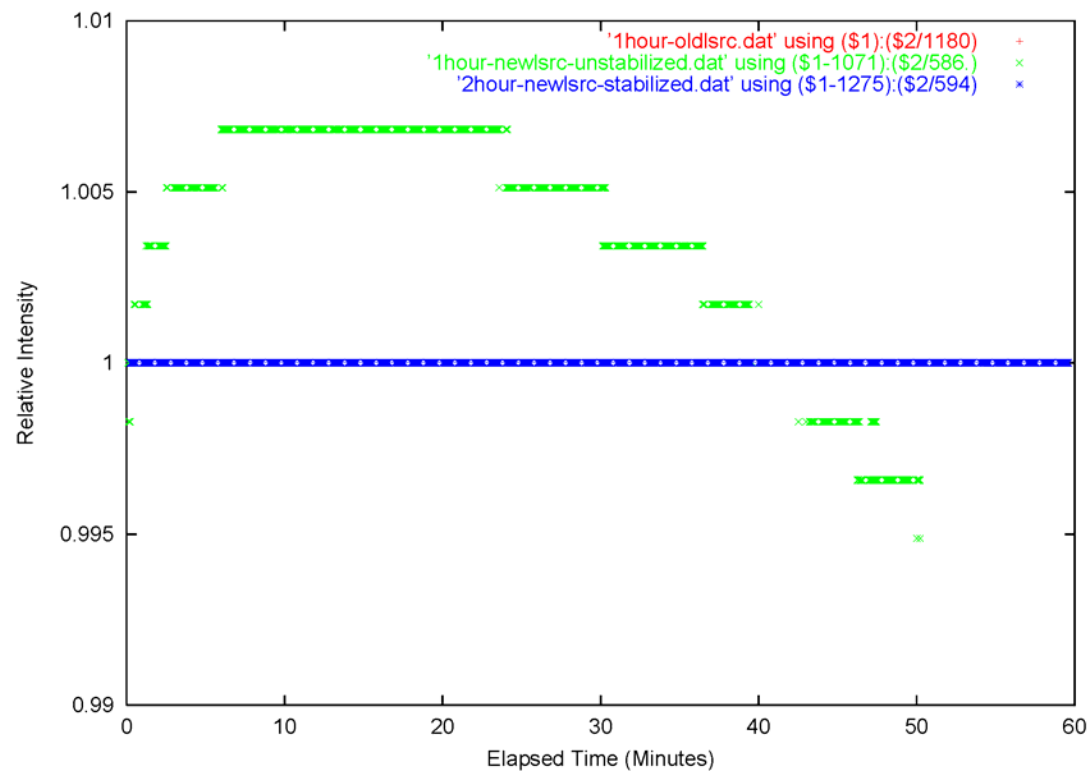


Diffraction  
limited spot  
size



# Improvements

## Light (In)Stability



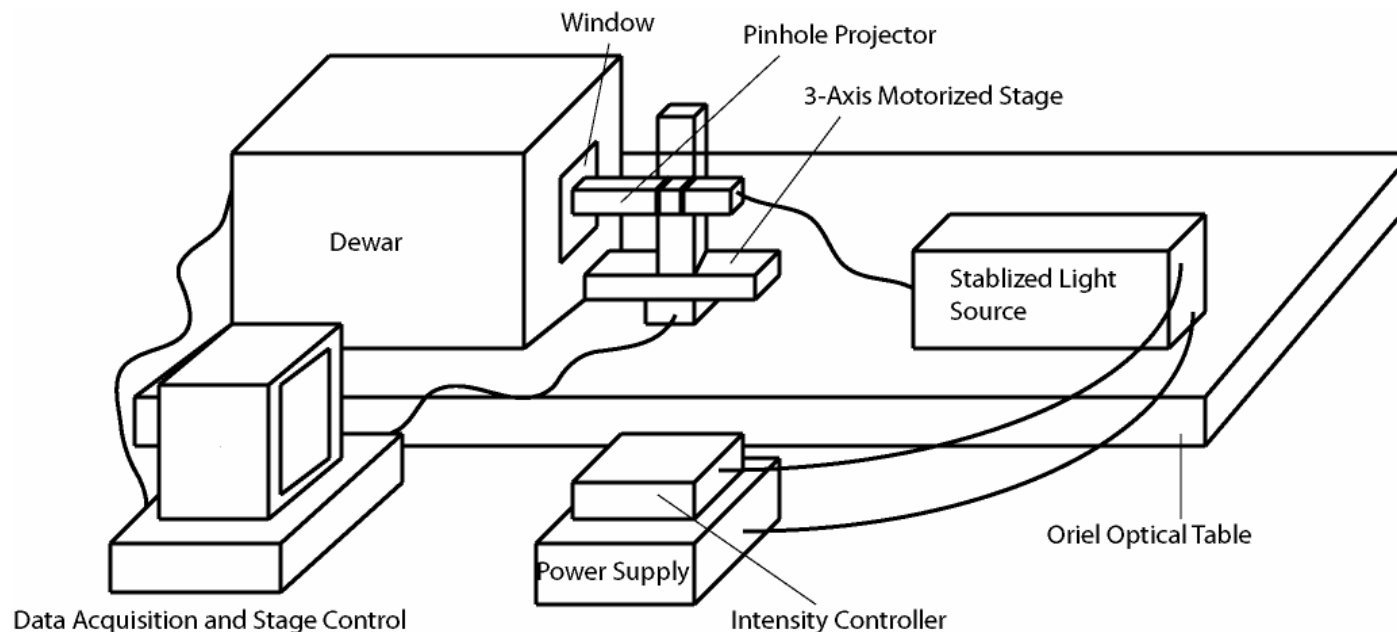
Need stable light source

(<1% variation) for:

- knife-edge scans
- PSF evaluation
- inter-pixel variation
- intra-pixel variation

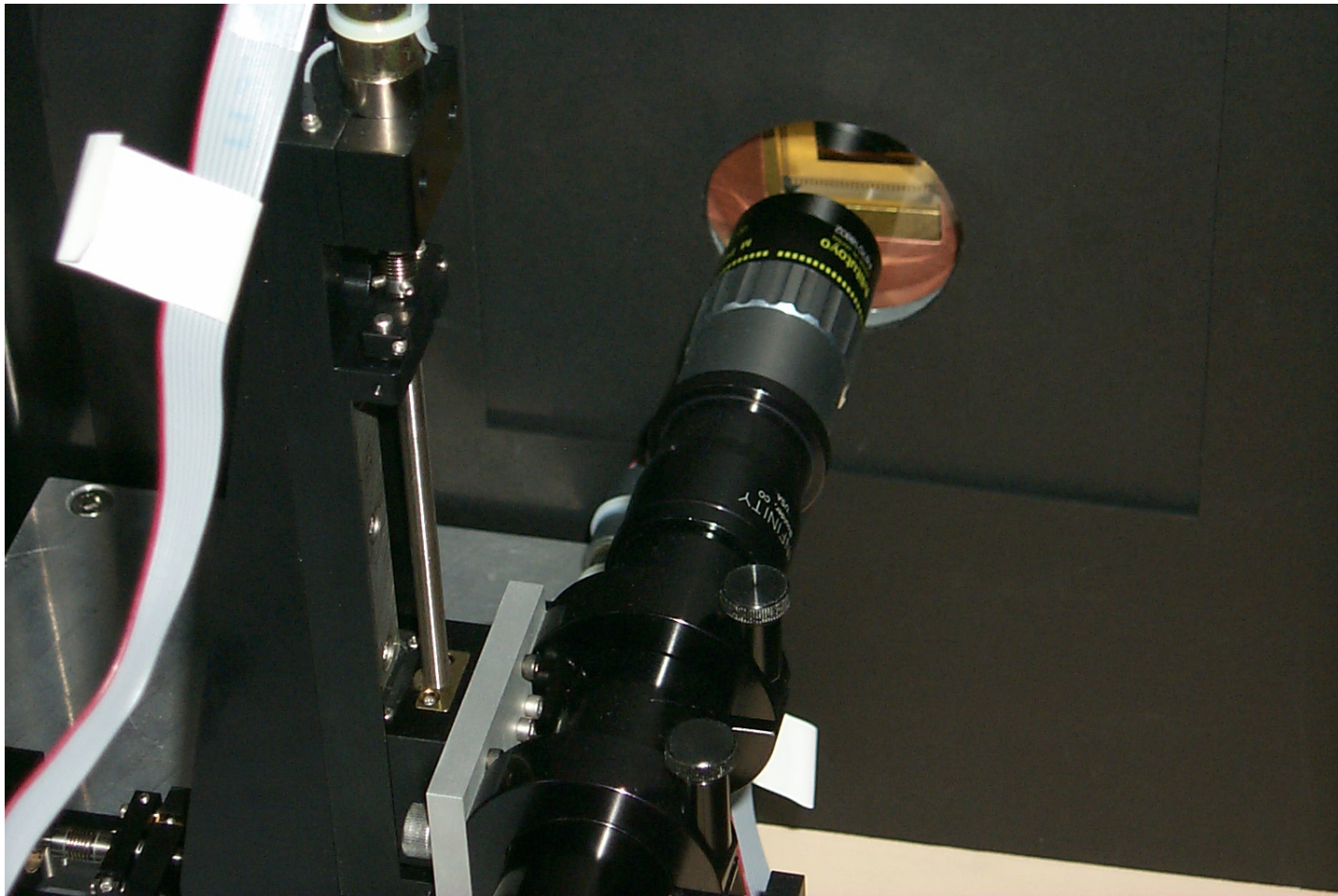
## Further Improvements

- Installed linear encoder on z-axis
  - improve speed, accuracy and repeatability of pixel scans
- Installed optical table
  - improve precision and repeatability of measurements
- many improvements to motion control and analysis software



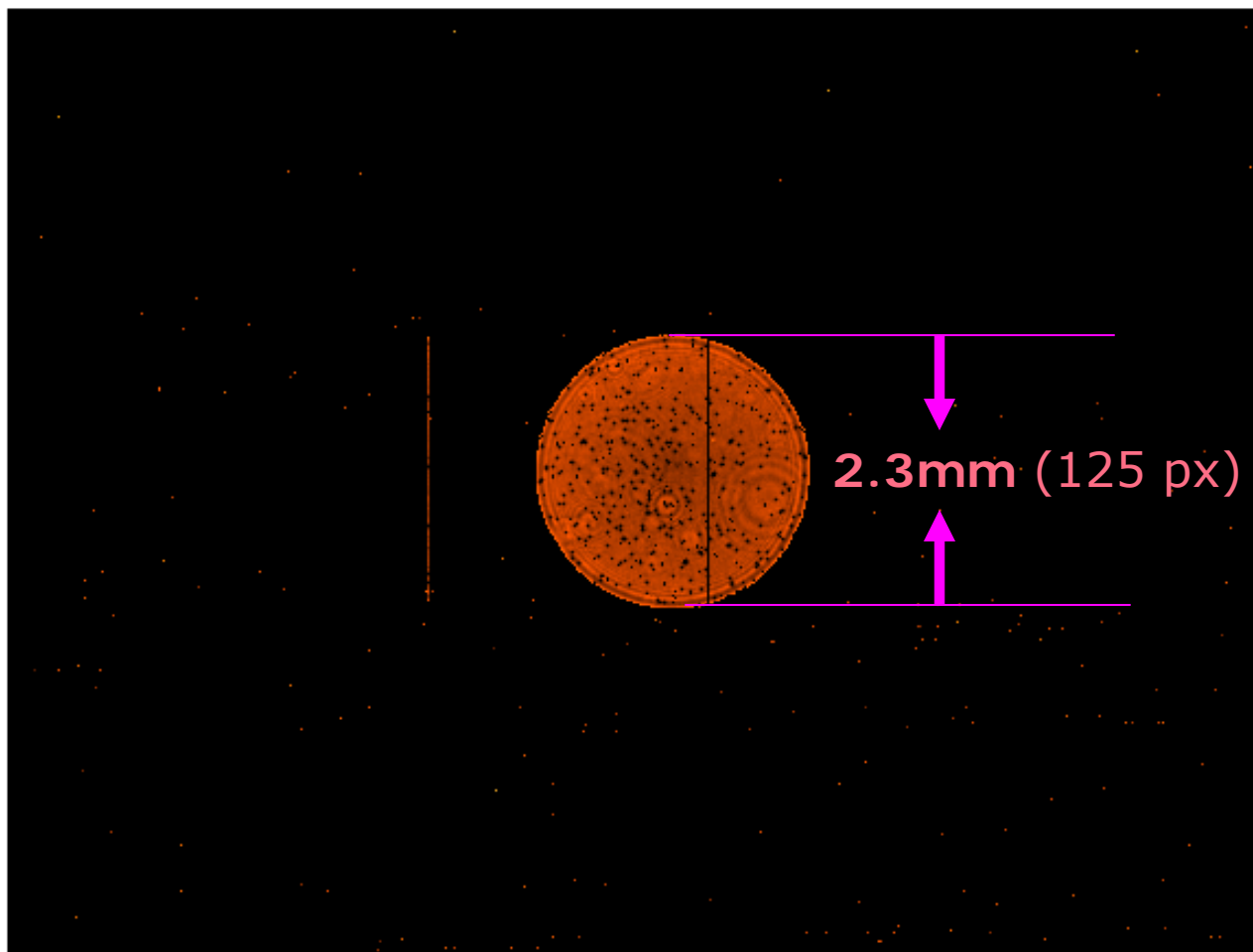
May 2004

## Putting a Spot on the InGaAs Detector



May 2004

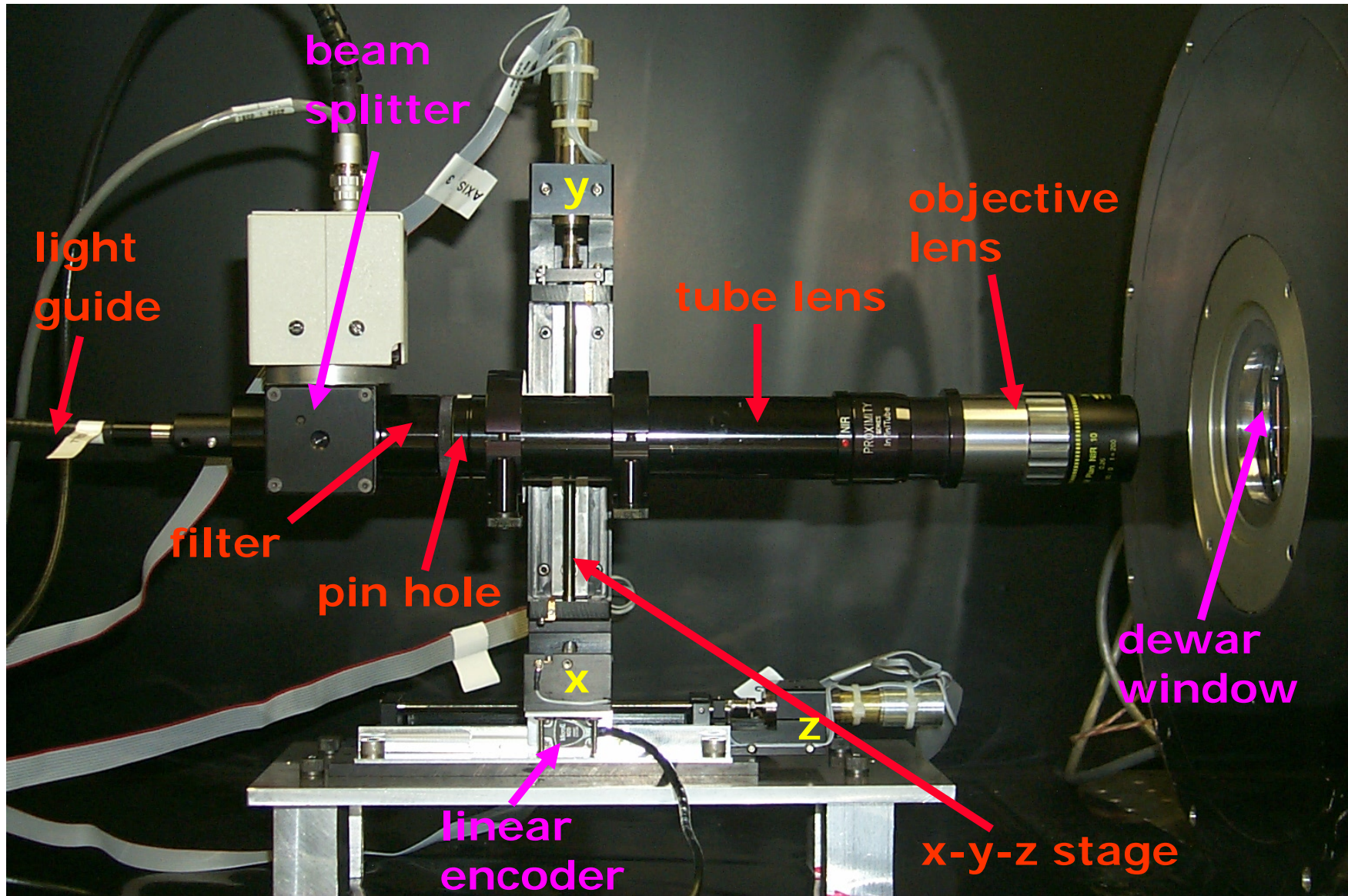
## Putting a Spot on the InGaAs Detector(II)



filter:  
 $1400 \pm 50$  nm

4.2 mm from  
focus

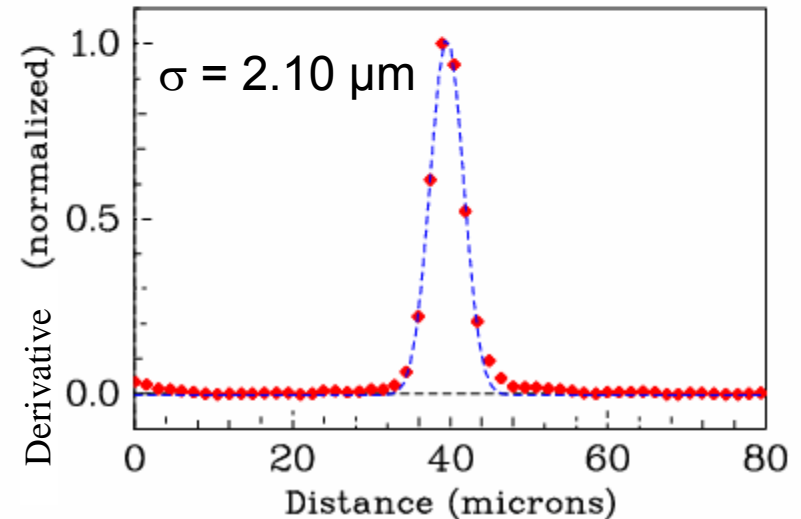
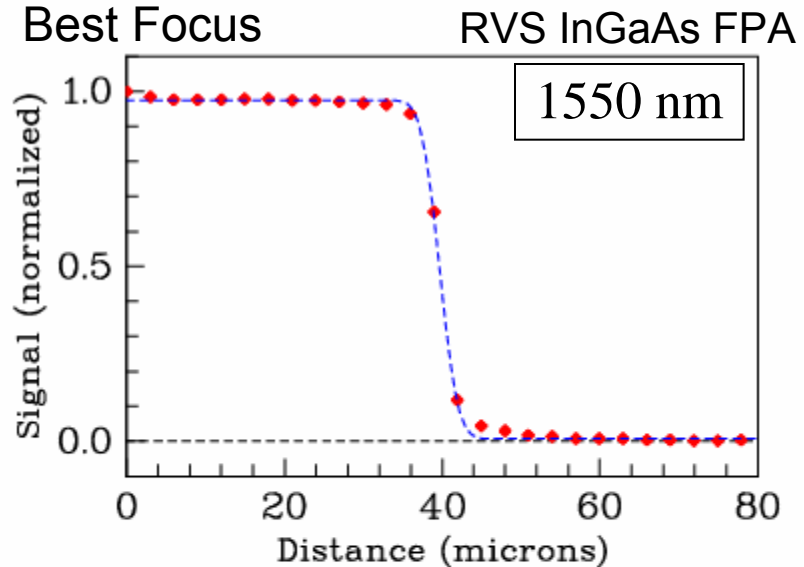
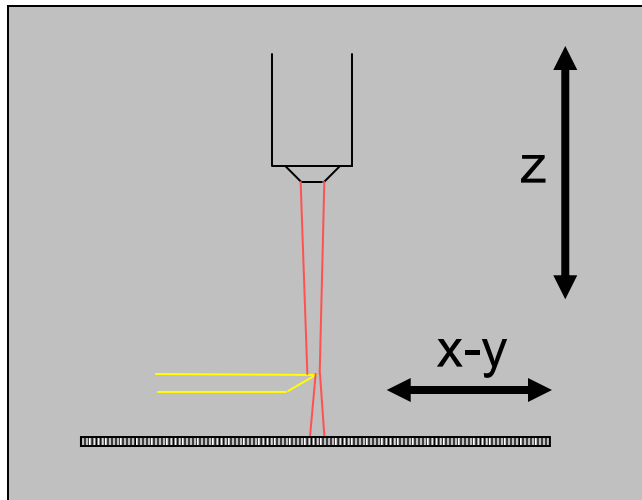
Summer 2004



# Knife-Edge Scan

## Characterize a beam spot

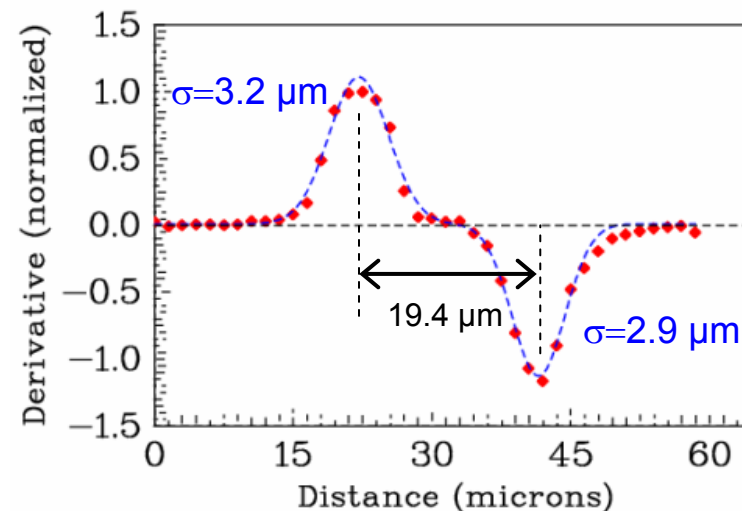
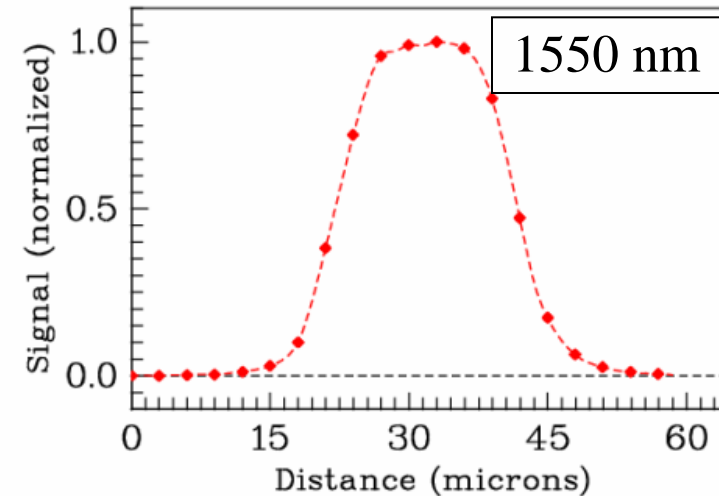
- A knife edge is placed  $\sim 6$  mm above the detector surface
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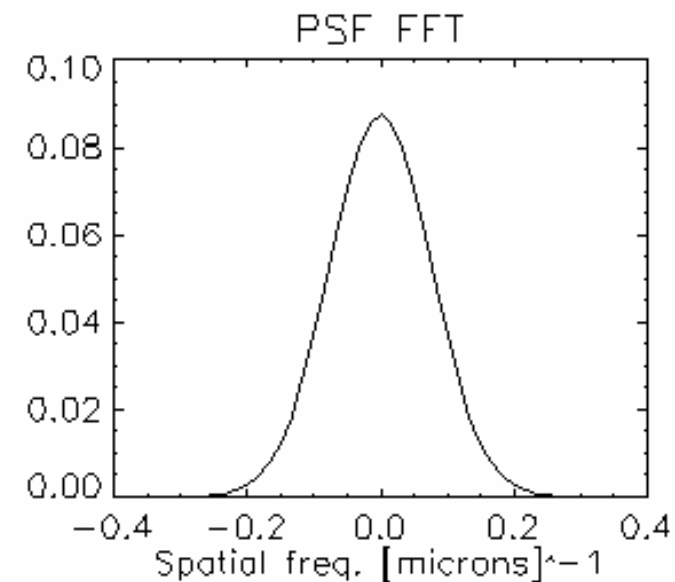
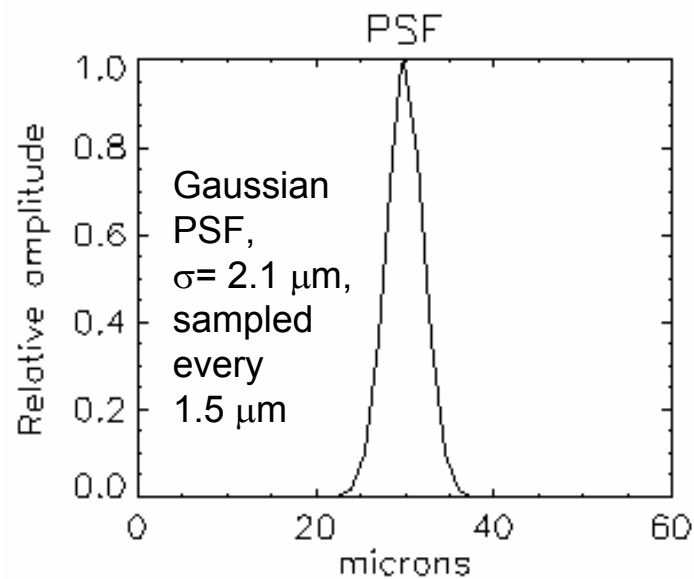
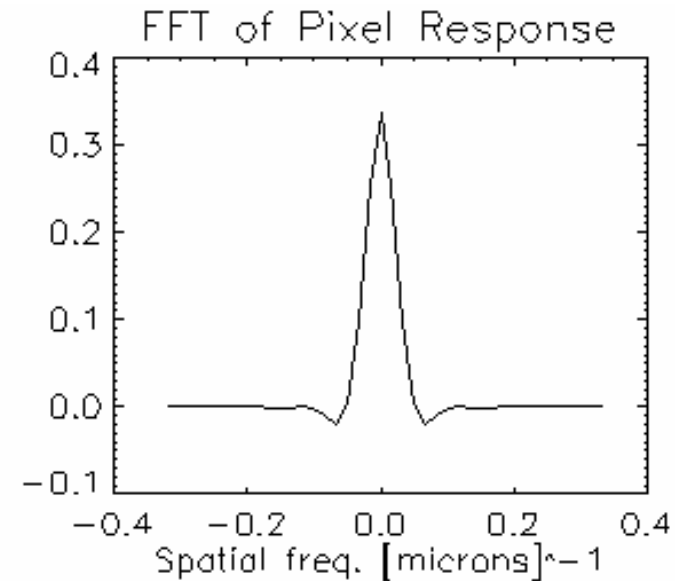
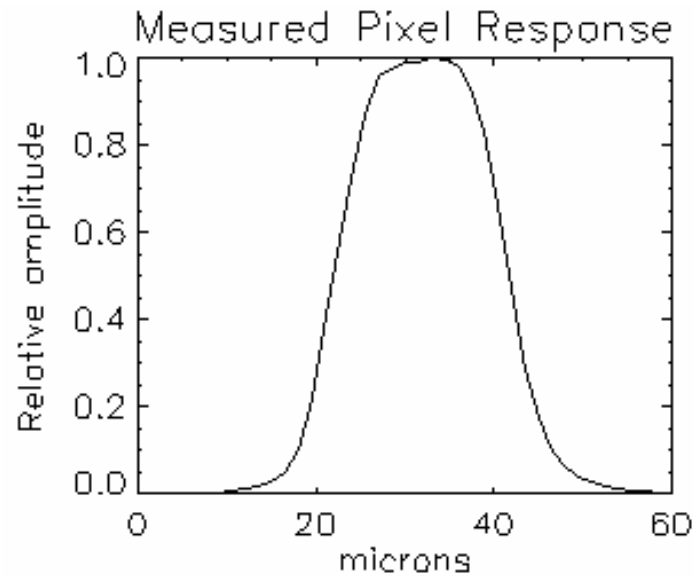
# Virtual Knife-Edge Scan

## Characterize a pixel

- Virtual knife edge scans (pixel boundary) used to focus Spot-o-Matic onto detector surface
- Intensity profile is a 1-dim convolution of Spot-o-Matic PSF with pixel response function
- Note that edge transition is  $\sigma = 2.9 - 3.2 \mu\text{m}$ , increased from the  $\sigma = 2.1 \mu\text{m}$  spot size obtained from the knife-edge scan, indicating intra-pixel sensitivity variation
- Pixel pitch ( $19.4 \mu\text{m}$  instead of  $20.0 \mu\text{m}$ ) is most likely an artifact of the  $1.5 \mu\text{m}$  discrete step size

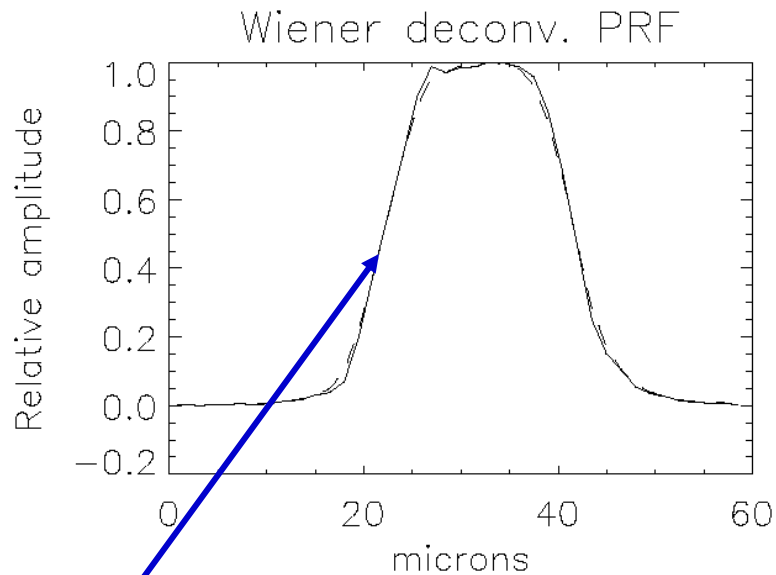
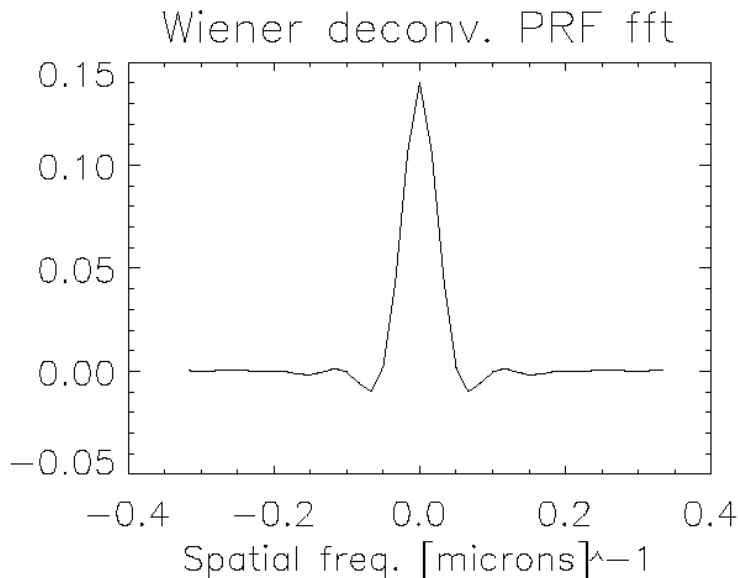


# Input Data for Deconvolution



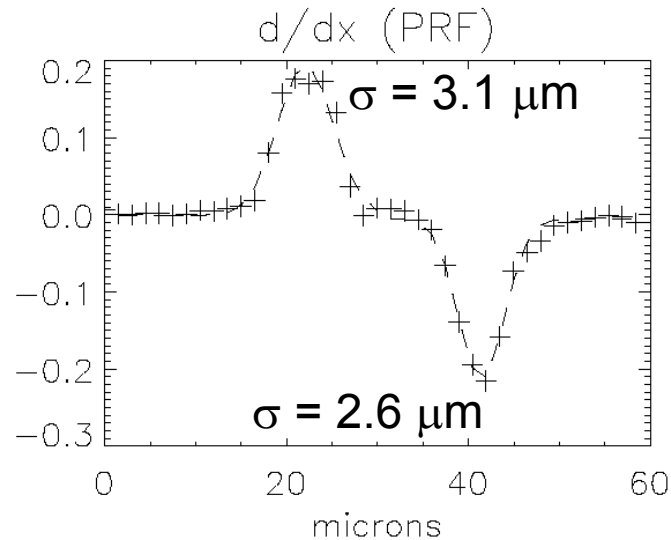


# Wiener Deconvolution

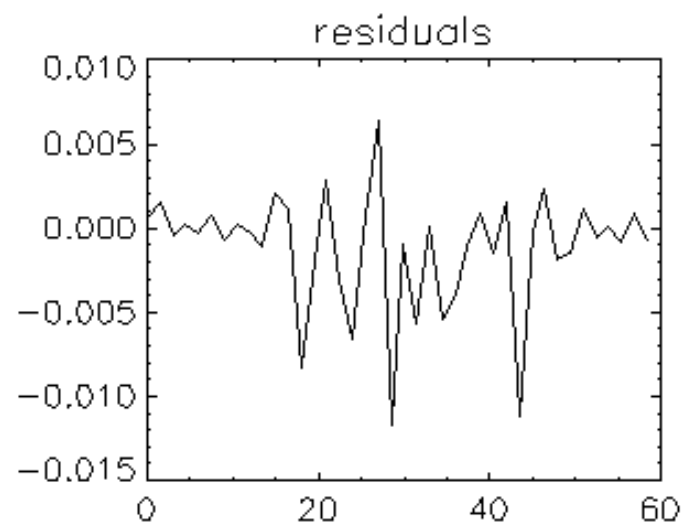
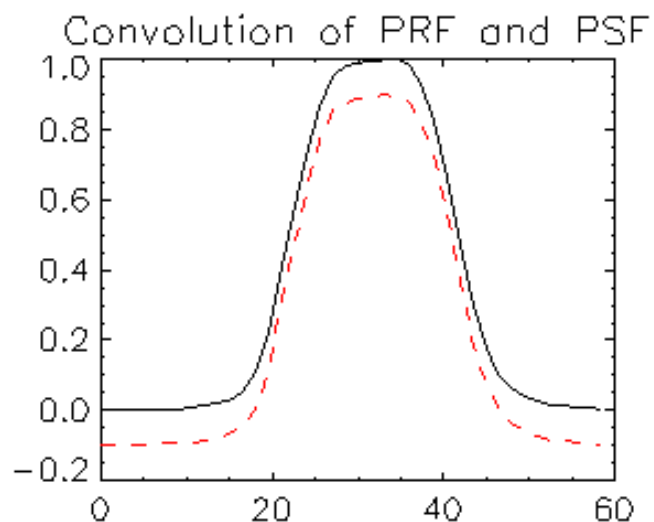


- $PSF(k) = FFT[psf(x)]$
- $MEASPRF(k) = FFT[measprf(x)]$
- $PRF(k) = FFT[prf(x)]$
- $PRF(k) = MEASPRF(k) * PSF(k) / [(PSF(k)^2 + 10^{-4})]$
- Simple deconvolution is too noisy.  
Wiener deconvolution filters high frequency noise.

• Note deconvolved PRF (solid curve) is "steeper" than measured PRF (dashed curve). "Dip" is artifact of reset persistence.



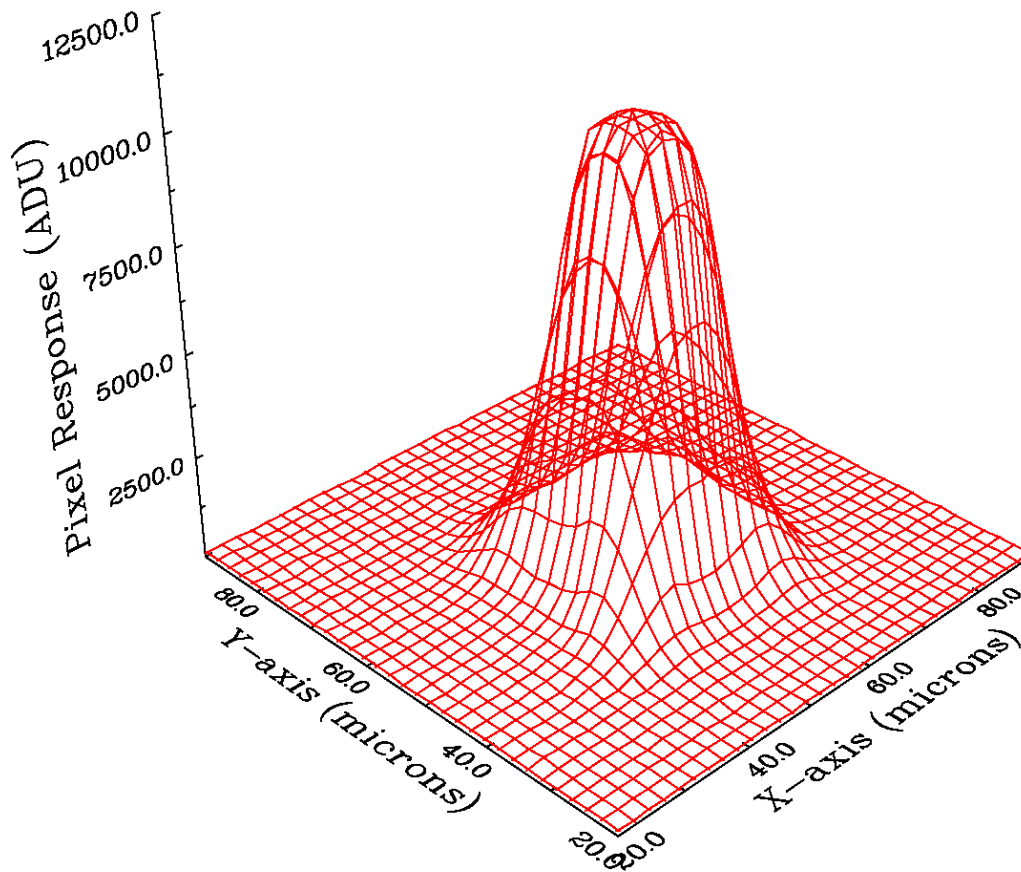
# Re-convolution as a Sanity Check



- “Re-convolution” (solid black curve) compares to measured PRF(x) (red dashed curve offset for clarity) with residuals at the  $\sim 1\%$  level or below

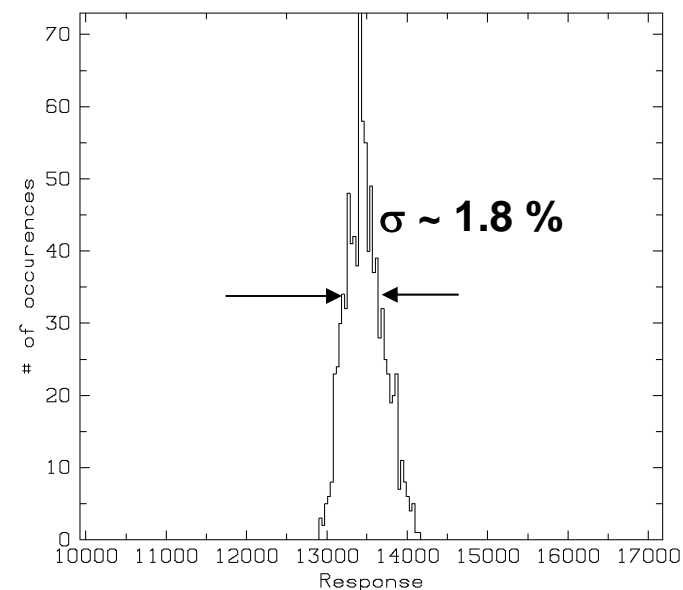
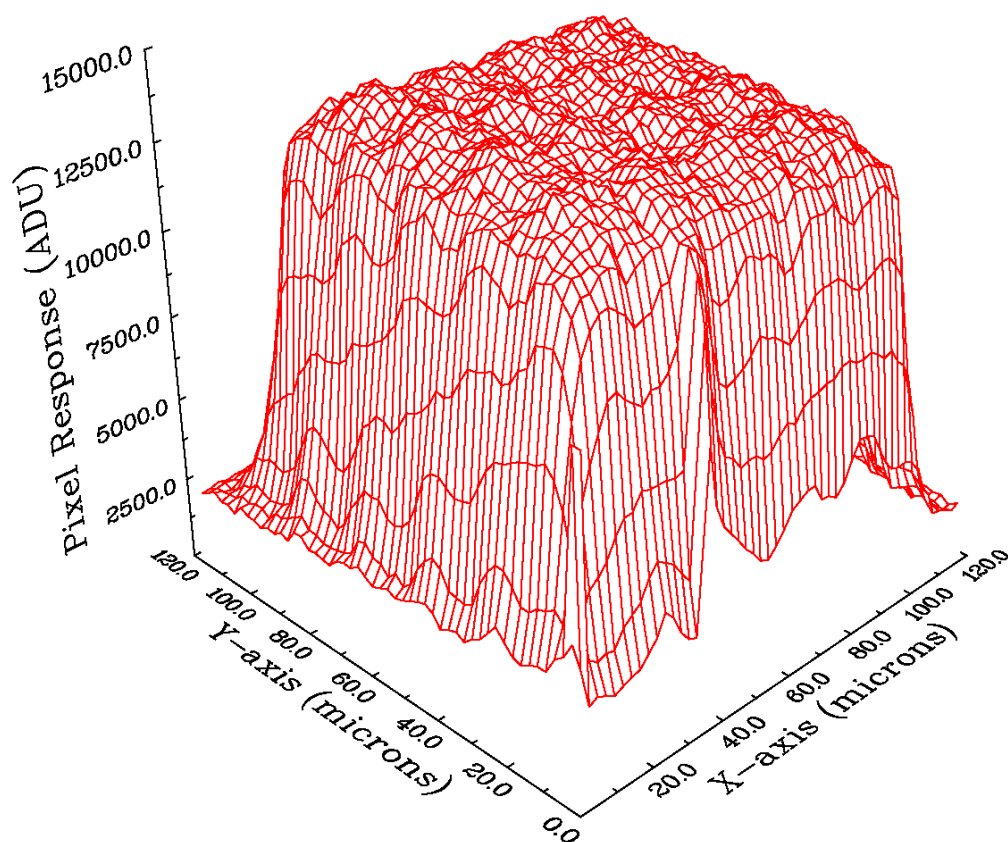
# Pixel Response Profile

Pixel scan at focus determines two-dimensional pixel response profile (convolution of 2D spot PSF with 2D pixel response function).



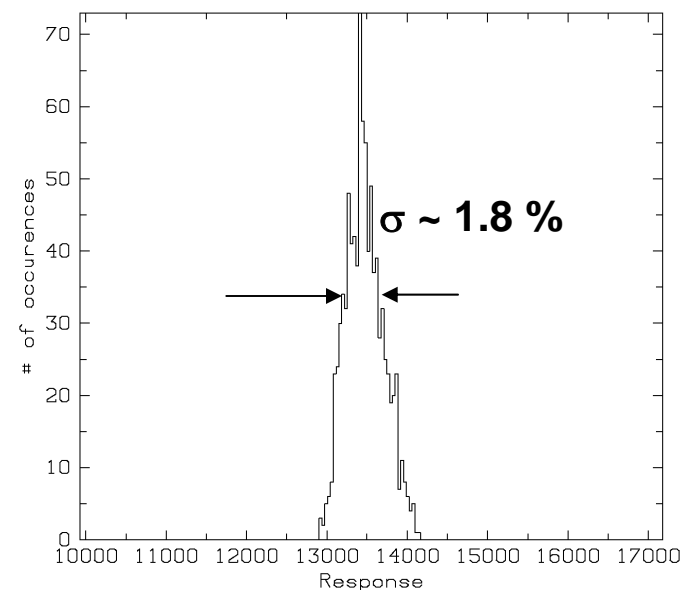
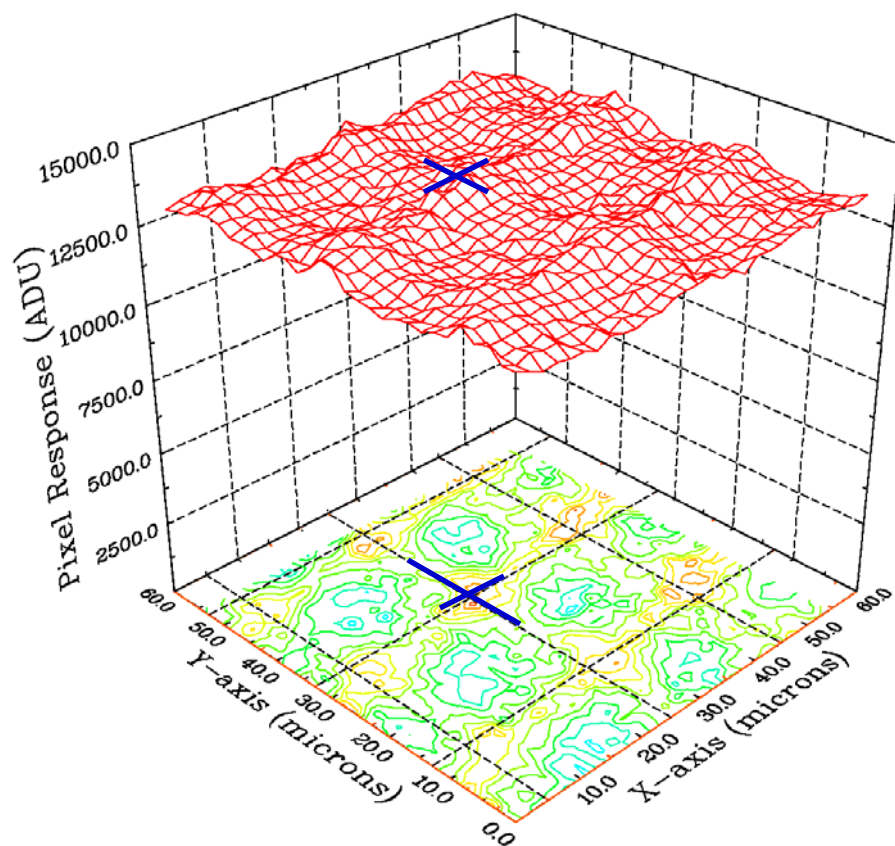
# Diffusion vs. Inefficient Charge Collection

Summation of adjacent pixels shows negligible deviation at pixel boundaries, suggesting diffusion rather than inefficient charge collection as the dominate source of intra-pixel variation in this InGaAs device.



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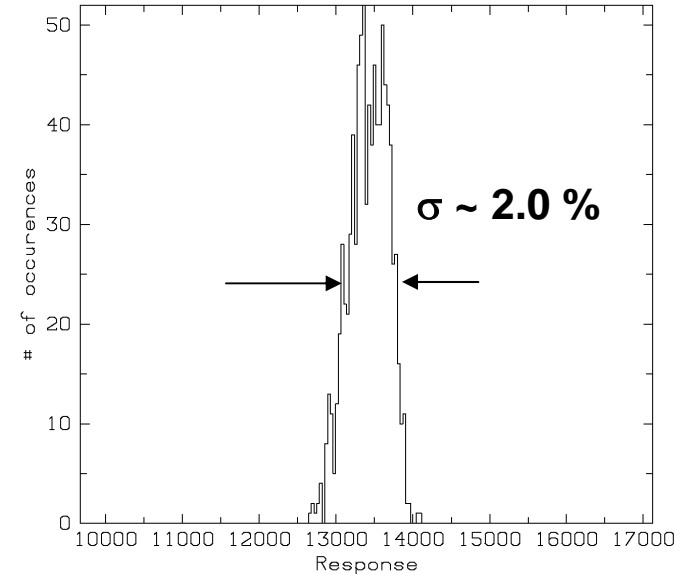
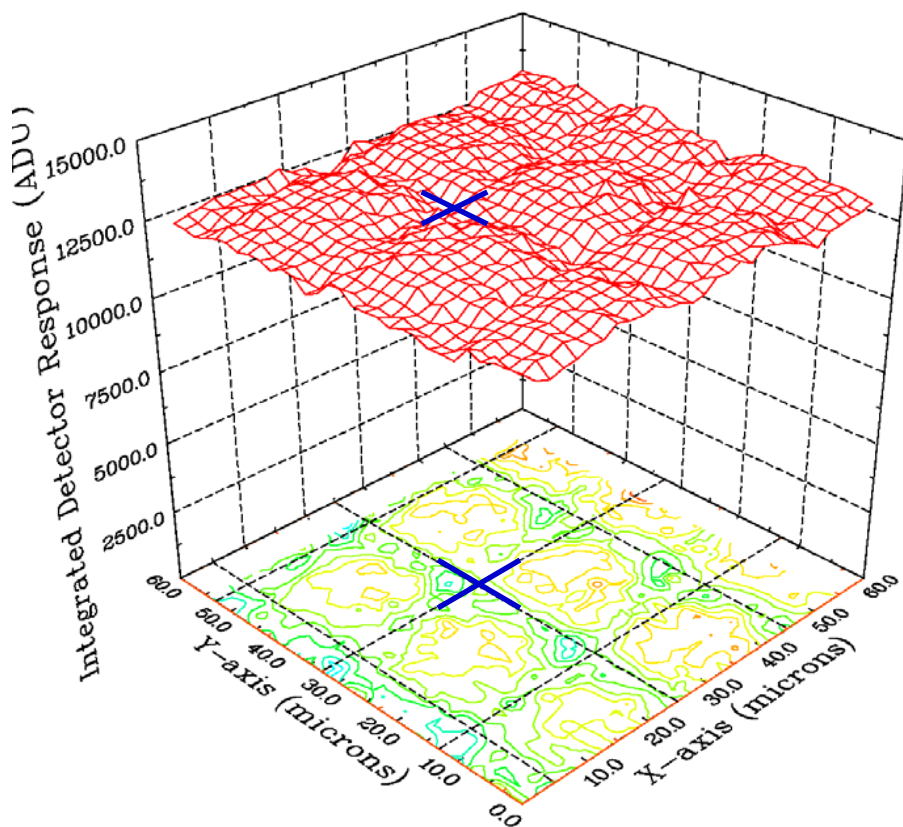
# Why 2-3 $\mu\text{m}$ ? and why Diffusion only?



- Simplest explanation:
  - photons get absorbed in a pixel
  - generating photoelectrons which diffuse across pixel boundaries near edges and are collected with unit efficiency
- The 2  $\mu\text{m}$  is significant:
  - because edge effects should be important when light is absorbed within  $\sim 1/2$  pixel thickness of the edge
- Martin Ettenberg of Sensors Unlimited confirms
  - InGaAs pixel thickness is 3.5  $\mu\text{m}$
- Fact that pixel sum is  $\sim$ flat across pixel boundaries confirms
  - there is a  $\sim 100\%$  chance of the electron being collected in some pixel.
  - consistent with large junction size (12  $\mu\text{m}$  square) in these detectors.

# Saturation Effects?

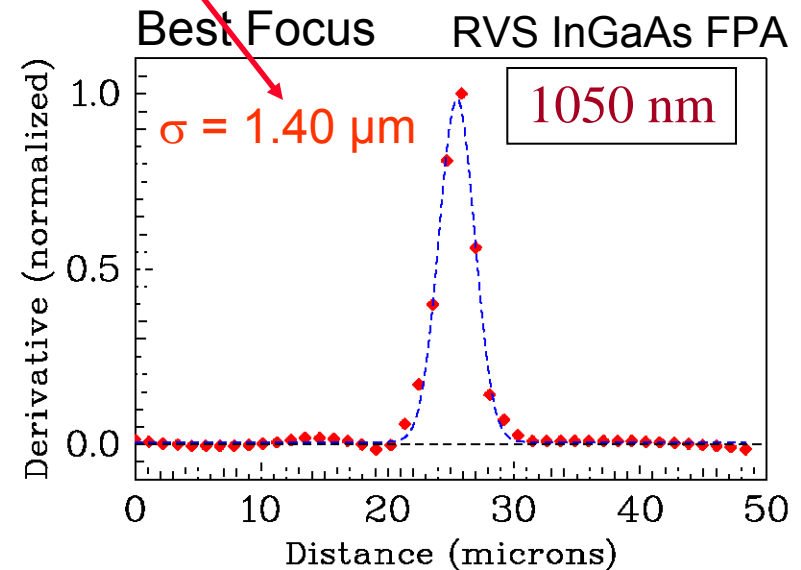
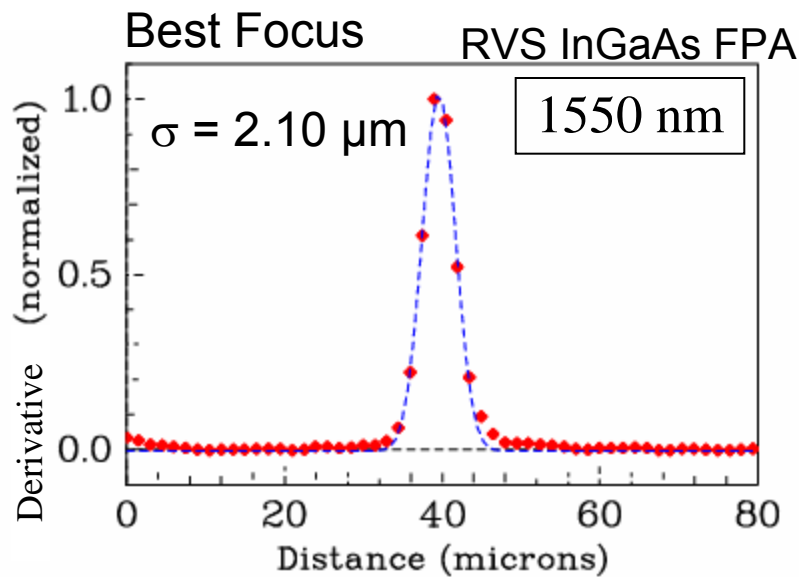
- Remove pixel response non-linearity:
  - saturation will produce ridges at pixel boundaries:
  - e.g, at boundary, signal is split between two pixels
  - sum of these two signals will be greater than saturated signal at center of pixel (~1% effects!!)



- dips after correction due to loss of charge? (minor effect)
- can measure these small effects

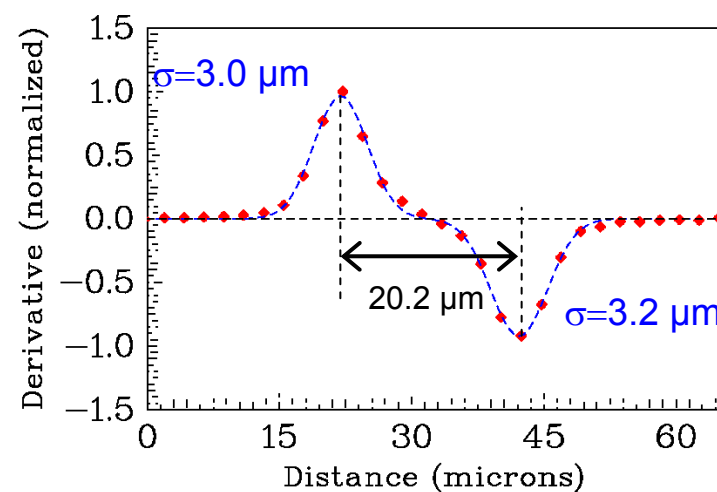
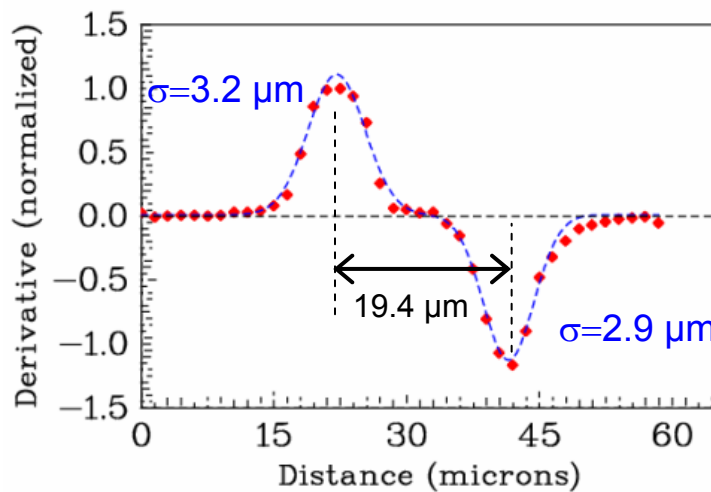
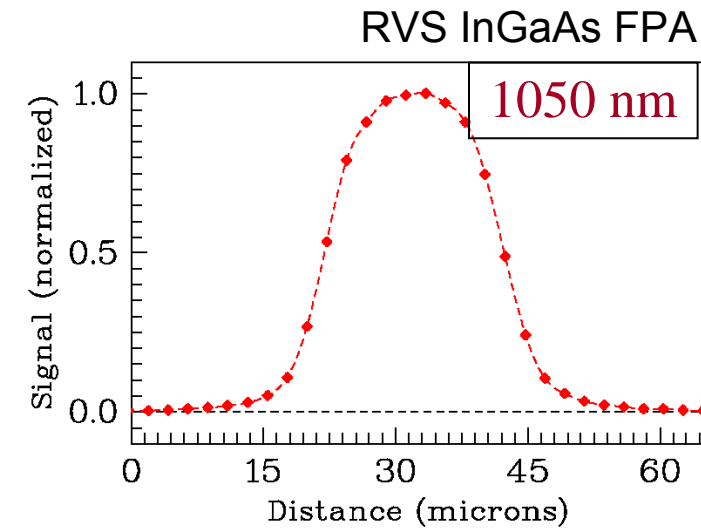
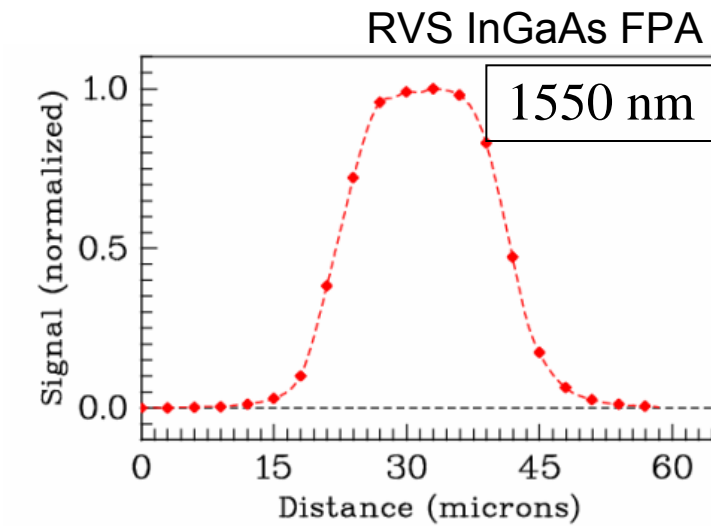
# Knife-Edge Scan at 1050 nm

- Diffraction limited spot size:  $\sigma_{\min} = 1.22\lambda / \text{N.A.}$
- Expect:  $\frac{1050 \text{ nm}}{1550 \text{ nm}} \cdot 2.10 \mu\text{m} = 1.42 \mu\text{m}$
- Excellent agreement





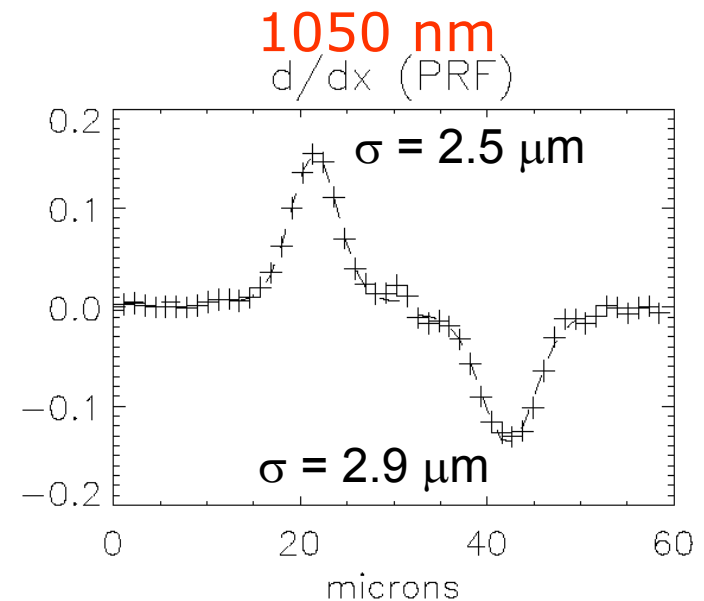
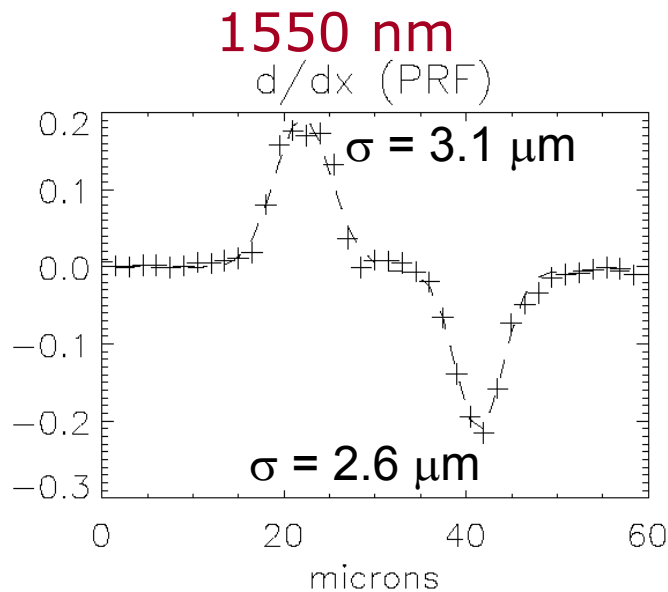
# Virtual Knife-Edge Scan at 1050 nm



- Need to do de-convolution

## Diffusion at 1050 nm

- Edge effects should be important when light is absorbed within  $\sim 1/2$  pixel thickness of the edge
- Light at 1050 nm penetrates pixel less before being absorbed — edge effects are larger
- Expect: more diffusion at 1050 nm than at 1550 nm
- Limitation of finite sampling ( $1.5 \mu\text{m} \rightarrow 0.5 \mu\text{m}$ )



# Plans

- Study pixel response for contiguous groups of pixels
  - study short and long range scale trends
  - repeat at various wavelengths, bias voltages, other parameters
  - compare different devices and different vendors
- Extract true 2-dim PSF
  - introduce knife-edges with a variety of orientations
  - is PRF symmetric?
- Use PRF as input to simulations
  - evaluate dithering schemes
    - random and  $n \times n$ , for integer and non-integer fractions of pixel sizes
- Test predictions in laboratory
  - defocussed spot to simulate SNAP PSF
    - ⇒ demonstrate required photometric accuracy with different dithering schemes
- Provide feedback to vendors as they modify manufacturing parameters
  - improve intra-pixel performance
  - alert them when required photometric accuracy is achieved

# Additional Equipment Needed

- Encoder system for x and y
  - get rid of backlash
  - reproducibly get to desired point in x-y-z
  - remove great source of occasional confusion interpreting data
- Receive most advanced Spot Projection Facility available to date for additional \$2,000!
  - Represents a unique facility for SNAP

# Conclusions

- The Spot-o-Matic is up and running
- The Raytheon InGaAs device shows a very flat pixel response with ~2-3  $\mu\text{m}$  edge effects dominated by diffusion
- A simple addition of adjacent pixels restores photometry to better than ~2%
- Higher resolution sampling will come next (0.5  $\mu\text{m}$  step size)
- Imperfect spot PSF determination, non-linearities in pixel response and persistence after reset all contribute to artifacts in the measurements. All of these can be refined and corrected with further measurements
- Will turn our attention to the RVS H2RG part 40
  - smaller junction size  $\rightarrow$  how is charge collection affected?
  - expect new results soon
  - detailed comparison among two vendors soon